VPC4000 was created in response to the need for high performance point-of-use regulators for modern semiconductor. Precise control of the gas discharge pressure at or near the tool served, makes possible for stable process control by a mass controller

Features

- High Flow capacity with minimal pressure drop and low supply pressure.
- Hurricane cleaning for "near absolute" contamination control.
- Capable of operating at a wide range of flow from 0.5cc/min to more than 800liters/min.
- Design and materials of construction ensure compatibility with high flowing corrosive gas.

Material of Construction

Wetted

Body.....SS 316L VIM/VAR
Diaphragm.....Hastelloy C-22
Seat .....SS 316L VIM/VAR
Seal .....PCTFE

Non-Wetted

Cap.....Stainless Steel
Knob.....Alum. Powder Coated

Operating Conditions

Max. Inlet.....600 psig (41.4 barg)
Outlet.....5~150 psig (10.3 barg)
Temp .....-40°F to 150°F (-40°C to 65°C)

Functional Performance

Design Burst Pressure.....1,500 psig (105 barg)
Design Proof Pressure .....750 psig (51 barg)
Flow Capacity .....C_V=1.0
(SEMI Flow Coefficient Test # F-32-0998)
Design Leak Rate:
Outboard.....$1x10^{-9}$scc/sec He
Inboard.....$1x10^{-9}$scc/sec He
Supply Pressure Effect .....4 psig (0.3barg) per 100 psig (6.8 barg)

Standard Configurations

¼", ⅜", ½", ¾", 1" Tube Stub
½", ¾", 1" Face Seal Fittings
See Regulator Porting Guide for other available options.

Surface Finishes

Standard Ra.....10 µin (0.254 µm)

Approximate Weight

4.6 lbs (2.1 kg)